

PATENT #3

**In the United States Patent and Trademark Office**

In re the application of

Robert A. SHEPHERD, Jr. et al.

Application No. 10/006,100

Filed: December 3, 2001

For: METHOD AND APPARATUS FOR  
PLASMA OPTIMIZATION IN  
WAFER PROCESSING



Examiner: Not Assigned

Art Unit: 3723

Docket No. NOVEP015

Date: March 28, 2002

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on **March 28, 2002**

Signed:

  
Diane Schwanbeck

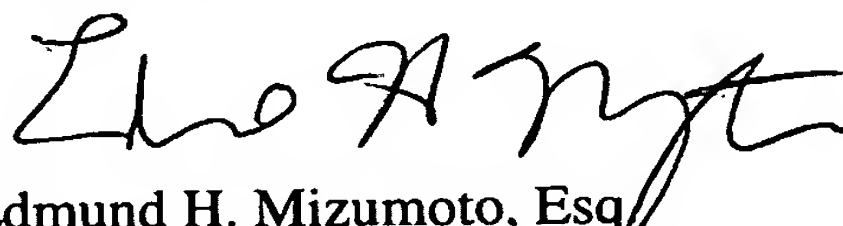
**Separate Letter to the Official Draftsperson**

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

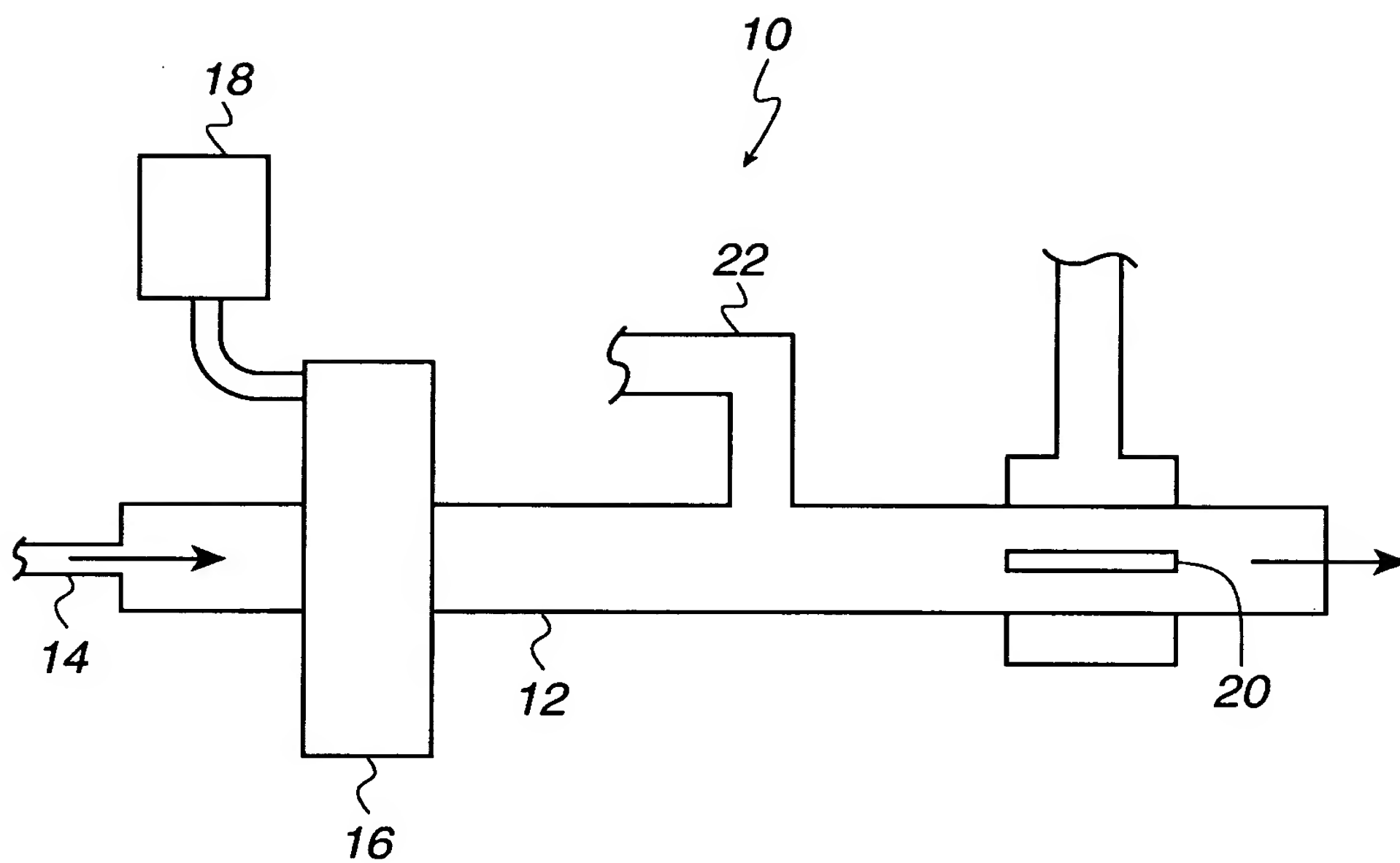
Applicants hereby attach six (6) sheets of formal drawings (Figures 1, 2A-C, and 3-4) for the above-identified patent application. In the event the Draftsperson has any questions concerning the formal drawings, he or she is respectfully requested to contact the undersigned. If any fees are due in connection with the filing of these drawings, then please charge such fees to our Deposit Account No. 50-0805 (Order No. NOVEP015).

Respectfully submitted,  
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*Fig. 1 (Prior Art)*

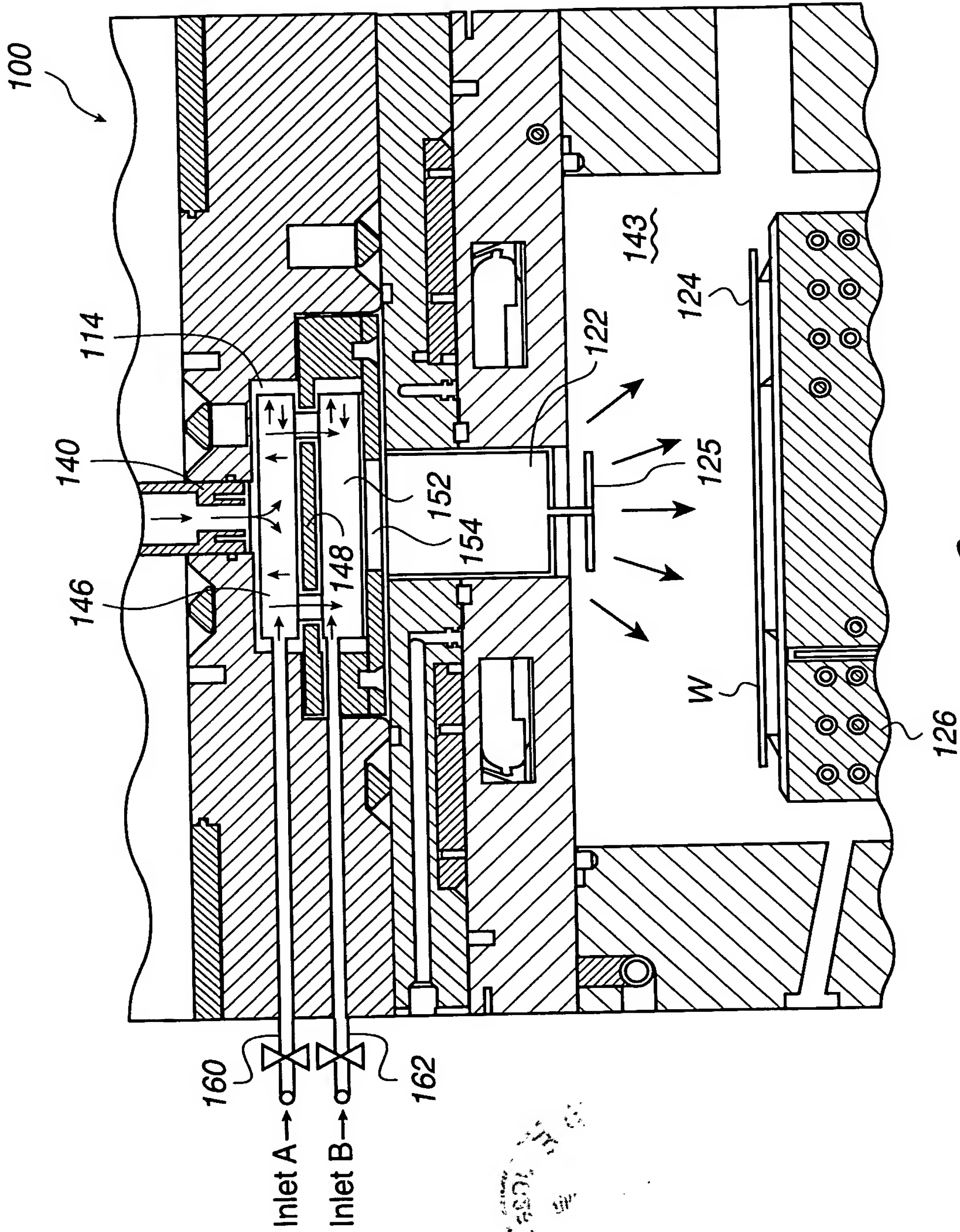
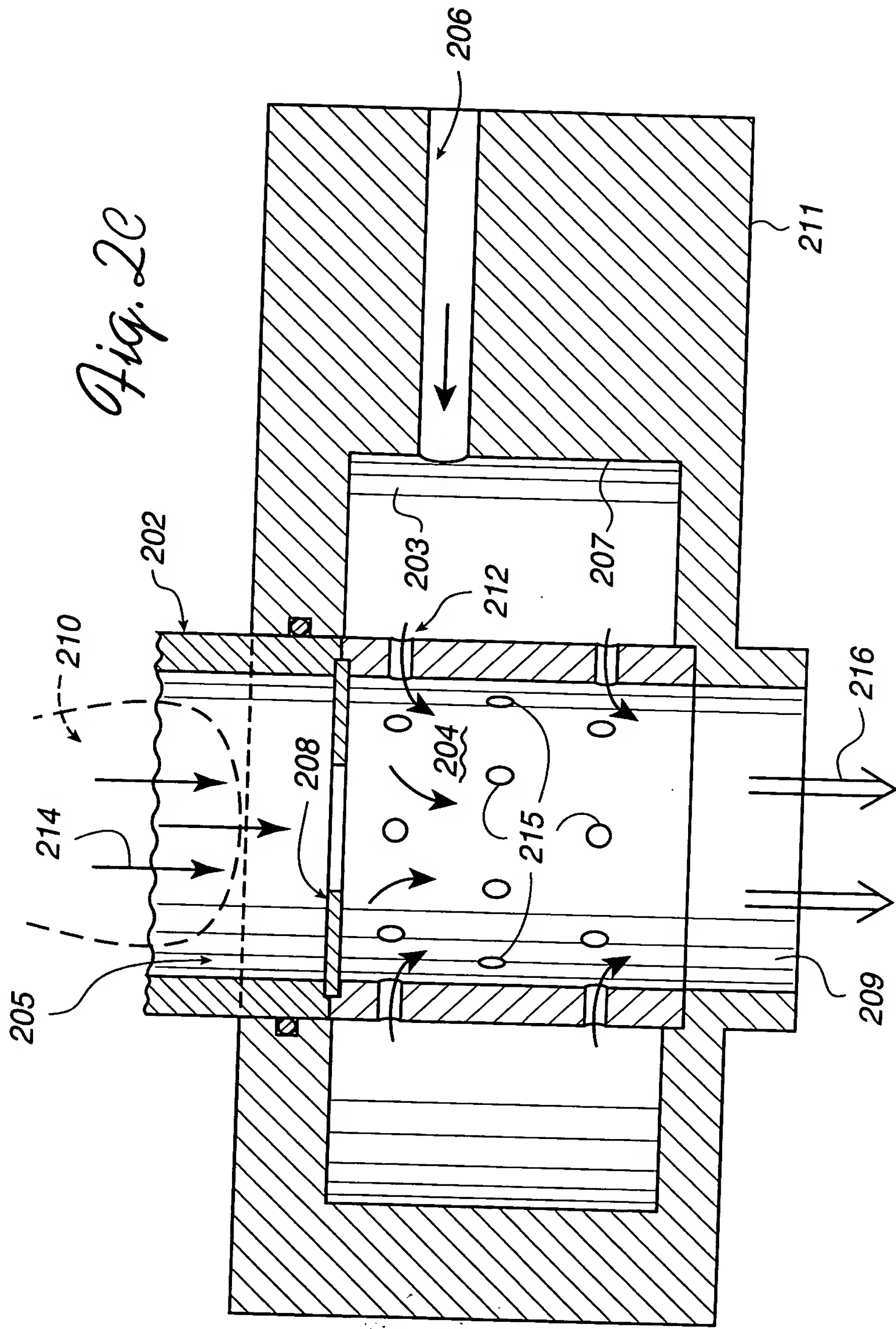


Fig. 2A





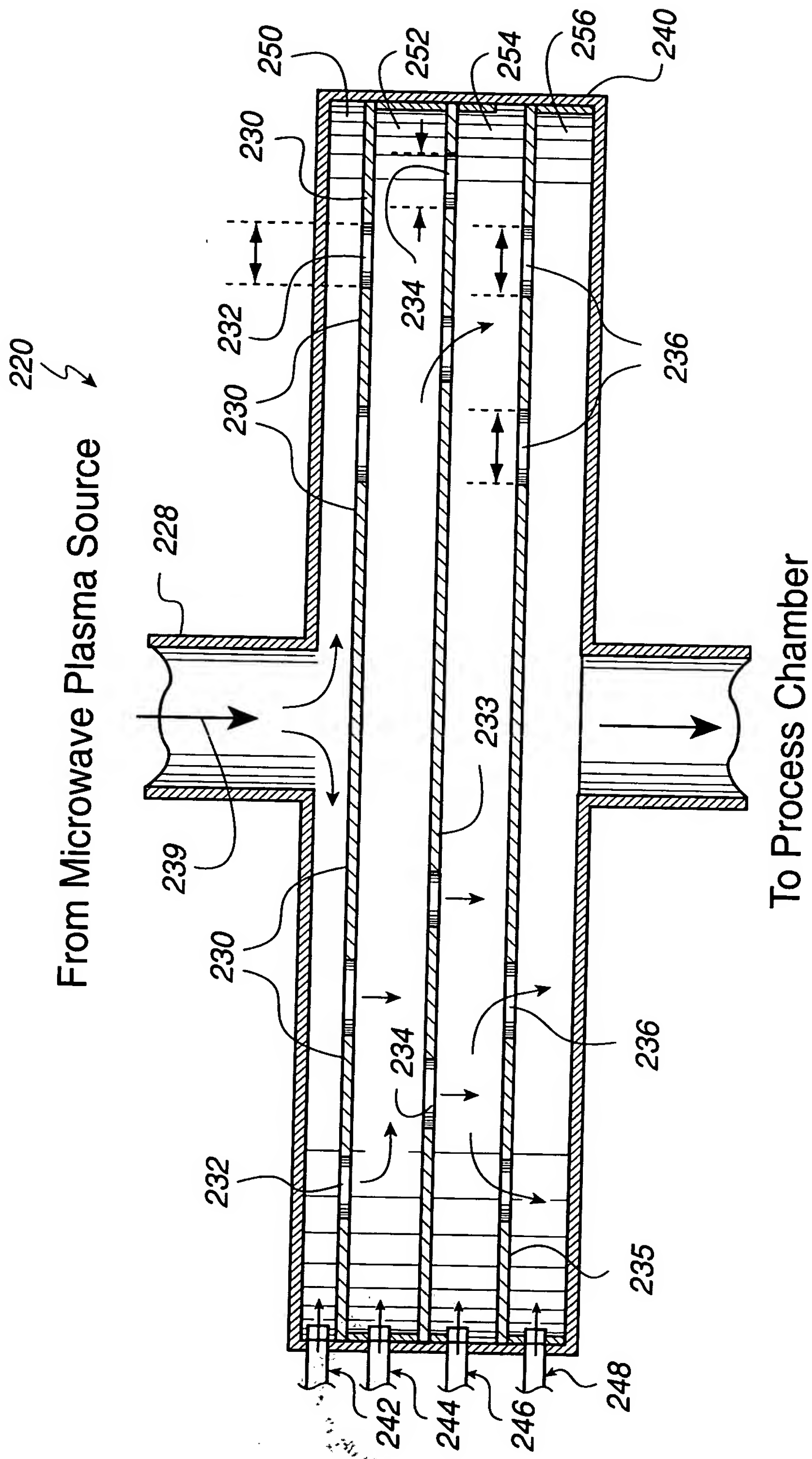


Fig. 3

2005-04-02

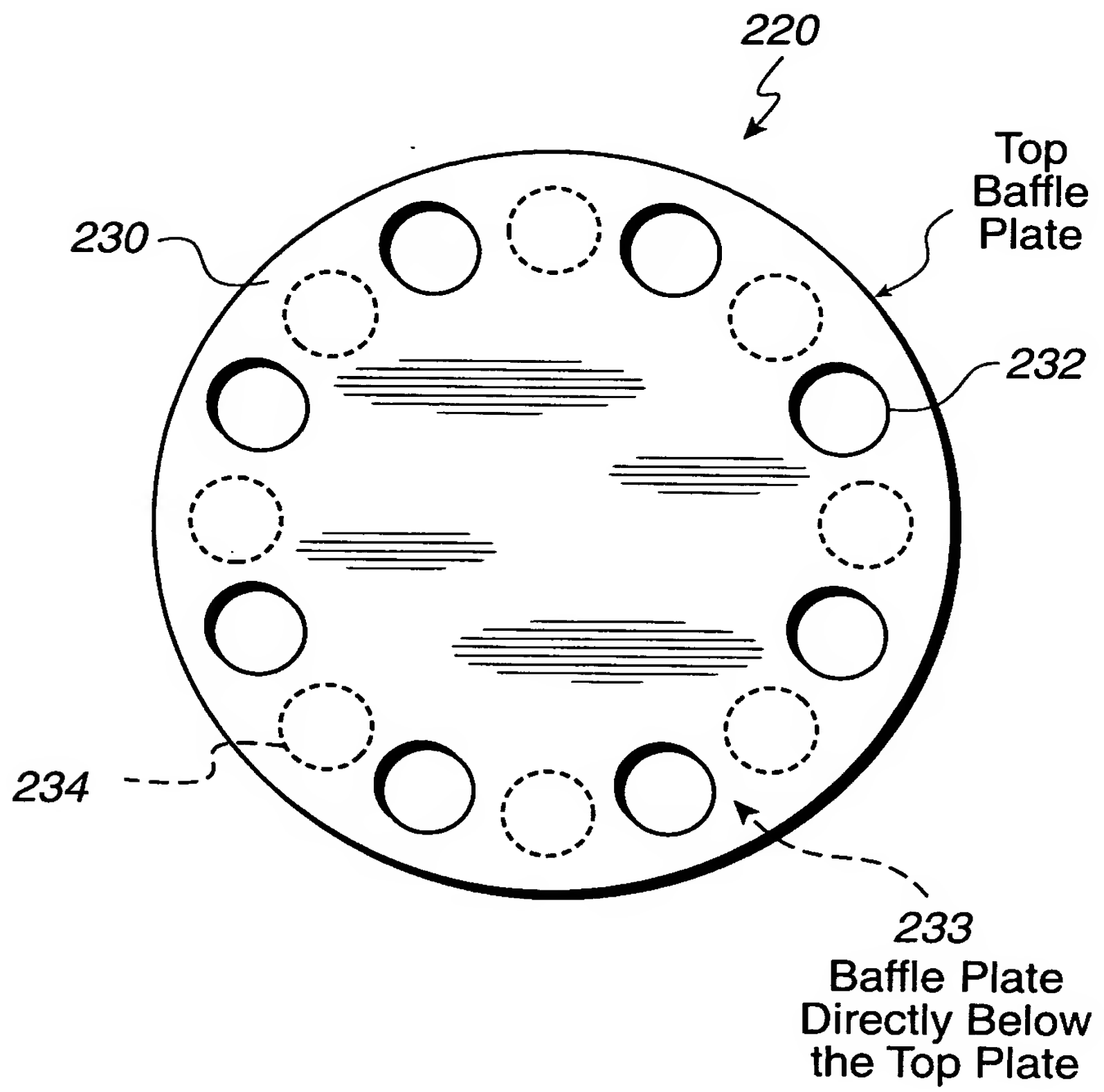


Fig. 4